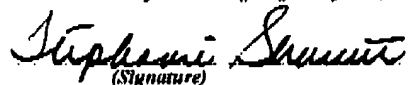


JAN 06 2006

CERTIFICATE OF TRANSMISSION BY FACSIMILE (37 CFR 1.8)			Docket No. 2003-0125-01
Applicant(s): Akins et al.			
Application No. 10/803,526	Filing Date March 17, 2004	Examiner K. Nguyen	Group Art Unit 2881
Invention HIGH REPETITION RATE LASER PRODUCED PLASMA EUV LIGHT SOURCE			
<p>I hereby certify that this <u>Response to Restriction (19 pages) & Fax Cover Sheet (1 page)</u> (Identify type of correspondence) is being facsimile transmitted to the United States Patent and Trademark Office (Fax. No. 571 273 8300 on <u>January 6, 2006</u> (Date)</p> <p style="text-align: right;">Stephanie Shurrett (Typed or Printed Name of Person Signing Certificate)  (Signature)</p> <p style="text-align: center;">Note: Each paper must have its own certificate of mailing.</p>			

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Atty. Docket No. 2003-0125-01
USSN 10/803,526

CERTIFICATE OF FACSIMILE TRANSMISSION

Date of Deposit January 6, 2006

I hereby certify that this paper is being sent via facsimile to (571) 273-8300 and addressed: Mail Stop Amendment,
Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on the date indicated above..... Stephanie Shurrett
(Name)

(Signature)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Akins et al.

Serial No.: 10/803,526

Filed: March 17, 2004

Title: A HIGH REPETITION RATE LASER
PRODUCED PLASMA EUV LIGHT
SOURCE

Examiner: K. Nguyen

Group Art Unit: 2881

Conf. No.: 5486

RESPONSE TO RESTRICTION

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed December 7, 2005, please amend the above-identified
application as follows:**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this
paper.**Remarks** begin on page 19 of this paper.